Accepted Manuscript

Title: Germanium Electrochemical Study and Its CMP

Application

Authors: Li Zhang, Baoguo Zhang, Baichen Pan, Chenwei

Wang

PII: S0169-4332(17)31575-1

DOI: http://dx.doi.org/doi:10.1016/j.apsusc.2017.05.220

Reference: APSUSC 36155

To appear in: APSUSC

Received date: 29-3-2017 Revised date: 23-5-2017 Accepted date: 24-5-2017

Please cite this article as: Li Zhang, Baoguo Zhang, Baichen Pan, Chenwei Wang, Germanium Electrochemical Study and Its CMP Application, Applied Surface Sciencehttp://dx.doi.org/10.1016/j.apsusc.2017.05.220

This is a PDF file of an unedited manuscript that has been accepted for publication. As a service to our customers we are providing this early version of the manuscript. The manuscript will undergo copyediting, typesetting, and review of the resulting proof before it is published in its final form. Please note that during the production process errors may be discovered which could affect the content, and all legal disclaimers that apply to the journal pertain.



ACCEPTED MANUSCRIPT

Germanium Electrochemical Study and Its CMP Application

Li Zhang a,b , Baoguo Zhang a,b , Baichen Pan a,b , Chenwei Wang b,

a. School of Electronic Information Engineering, Hebei University of Technology, Tianjin 300130, P. R. China

b. Tianjin Key Laboratory of Electronic Materials and Devices, Tianjin 300130, P. R. China

Highlights

- The corrosivity for Ge with H₂O₂ is stronger in alkaline media than in acidic one, and it
 increases with pH.
- • Electrochemical study is consistent with CMP experiments.
- NaCl is an activator for Ge corrosion.
- Dodecylamine is an inhibitor for Ge corrosion.
- Slurry in our research has a good polish selectivity to Ge, compared to SiO₂.

Abstract

When the feature size of ultra-large scale integrated (ULSI) circuit shrinks to sub10nm, germanium (Ge) as a novel material with high hole mobility is needed for
further development. Chemical mechanical polishing (CMP) is an important process
for the integration of channel materials into silicon wafer. In this paper, starting with
electrochemical studies of Ge, different types and concentrations of oxidants for Ge
corrosion were investigated; then the effect of NaCl and Dodecylamine for Ge
activation and inhibition were studied. After that, corresponding CMP experiments
were conducted, which confirmed the results of electrochemical experiments.

Download English Version:

https://daneshyari.com/en/article/5347540

Download Persian Version:

https://daneshyari.com/article/5347540

<u>Daneshyari.com</u>